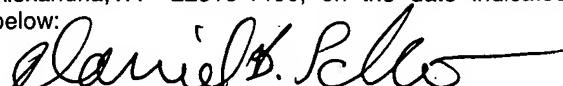


I hereby certify that this correspondence is being deposited with the United States Postal Service, with sufficient postage, as first class mail in an envelope addressed to: Mail Stop Patent Application, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date indicated below:



Daniel B. Schein, Ph. D., Esq.

Reg. No. 33,551

15 November 2003

Date of Signature

Our Case No.: 11470-4

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

SNOWDON et al.

Serial No.: To be assigned

Filing Date: To be assigned

For: A REGULAR ARRAY OF  
MICROSCOPIC STRUCTURES ON A  
SUBSTRATE AND DEVICES  
INCORPORATING SAME

A Continuation-in-part Application of

Serial No.: 10/168,239

Filed June 17, 2002

Parent Application Examiner: Quoc Dinh  
Hoang

Parent Application Group Art Unit No.: 2818

INFORMATION DISCLOSURE STATEMENT

Mail Stop Patent Application  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56, it is respectfully requested that this Information Disclosure Statement be entered and the documents on the attached Form PTO-1449 be considered by the Examiner and made of record. Copies of

the listed documents required by 37 C.F.R. § 1.98(a)(2) are enclosed for the convenience of the Examiner.

In accordance with 37 C.F.R. § 1.97(g),(h), this Information Disclosure Statement is not to be construed as a representation that a search has been made and is not to be construed to be an admission that the information cited is, or is considered to be, material to patentability as defined in 37 C.F.R. § 1.56(b).

This Information Disclosure Statement is being filed with the application and prior to the receipt of the first Official Action reflecting an examination on the merits and hence is believed to be timely filed in accordance with 37 C.F.R. § 1.97(b). No fees are believed to be due in connection with filing of this Information Disclosure Statement, however, should any fees under 37 C.F.R. §§ 1.16 to 1.21 be deemed necessary for any reason relating to these material, the Commissioner is hereby authorized to deduct said fees from Brinks Hofer Gilson & Lione Deposit Account No. 23-1925. A duplicate copy of this document is enclosed.

This application is a continuation-in-part application of U.S. Serial No. 10/168,239, filed June 17, 2002 and is relied upon for an earlier filing dated under 35 U.S.C. § 120.

Applicant(s) respectfully request that the listed documents be made of record in the present case.

Respectfully submitted,



Daniel B. Schein, Ph.D., Esq.  
Registration No.: 33,551  
Attorney for Applicant(s)

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FORM PTO-1449	SERIAL NO. To be assigned	CASE NO. 11470-4
<b>LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT</b>  (use several sheets if necessary)	FILING DATE To be assigned	GROUP ART UNIT To be assigned
	APPLICANT(S): SNOWDON et al.	

**REFERENCE DESIGNATION**      **U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS/ SUBCLASS	FILING DATE
	A1 6,314,019 B1	11/6/2001	Kuekes et al.		
	A2 6,248,674 B1	6/19/2001	Kamins et al.		
	A3 6,128,214	10/3/2000	Kuekes et al.		
	A4 5,155,826	10/13/1992	Fadem		
	A6 4,490,783	12/25/1984	McDonough et al.		
	A5 4,807,218	02/21/1989	Gerber		

**FOREIGN PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS/ SUBCLASS	TRANSLATION YES NO
	A6 PCT/GB01/00222	6/12/2001	European Patent Office - PCT Written Opinion		

EXAMINER INITIAL	OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)	
	A7	Batzill, M., et al., "Preferential Sputtering Induced Stress Domains and Mesoscopic Phase Separation on CaF <sub>2</sub> (111)," <i>Physical Review Letters</i> , Volume 85, Number 4, pp. 780-783, (July 24, 2000).
	A8	Facsko, S., et al., "Formation of Ordered Nanoscale Semiconductor Dots by Ion Sputtering," <i>Science</i> , Volume 285, pp. 1551-1553, (September 3, 1999).
	A9	Wissing, M., et al., "An Apparatus for Glancing Incidence Ion Beam Polishing and Characterization of Surfaces to Angstrom-Scale Root-Mean-Square Roughness," <i>Rev. Sci. Instrum.</i> , Volume 67, Number 12, pp. 4314-4320, (December 1996).

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.